

Supporting information

Solution processed Li_5AlO_4 dielectric for low voltage transistor fabrication and its application for metal oxide/quantum dot heterojunction phototransistor

Anand Sharma[‡], Nitesh k. Chourasia[‡], Anumol Sugathan[¶], Yogesh Kumar⁺, Satyabrata Jit⁺, Shun-Wei Liu[¶], Anshu Pandey[¶], Sajal Biring[¶] and Bhola N. Pal^{‡*}

[‡]School of Materials Science and Technology, Indian Institute of Technology (Banaras Hindu University),

⁺Dept. of Electronics Engineering, Indian Institute of Technology (Banaras Hindu University),
Varanasi-221005, India

[¶]Solid State and Structural Chemistry Unit, Indian Institute of Science, Bangalore 560012, India

[¶]Department of Electronic Engineering, Ming Chi University of Technology, New Taipei City, Taiwan 243

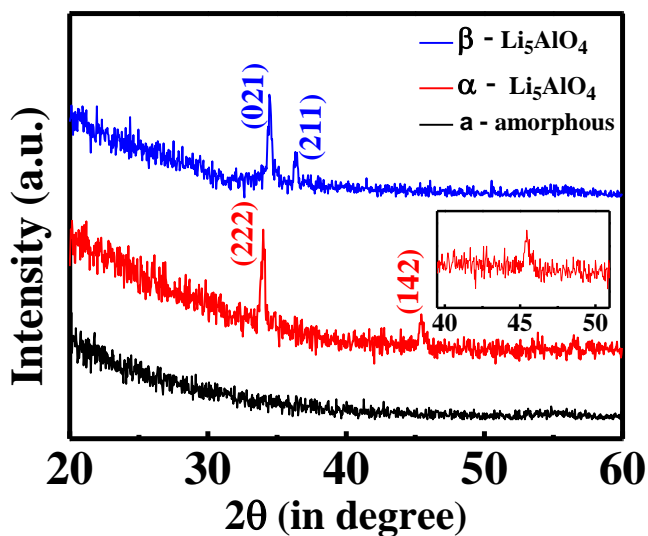


Fig. 1S. Grazing incidence X-ray diffraction (GIXRD) analysis of Li_5AlO_4 dielectric thin film

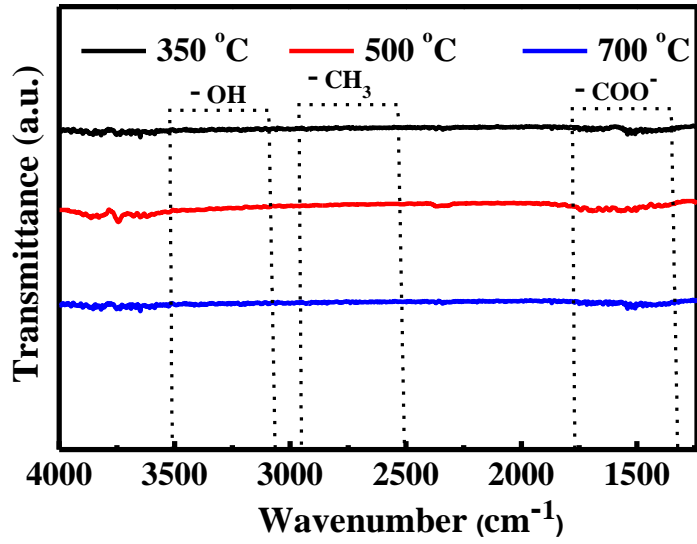


Fig. 2S. FTIR analysis of Li_5AlO_4 dielectric thin film anneal at 350 °C, 500 °C and 700 °C

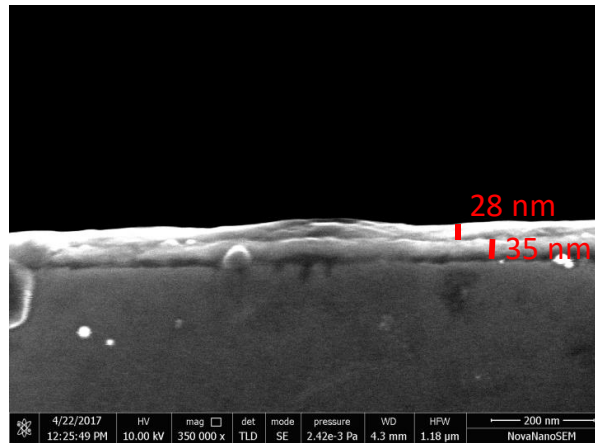


Fig. 3S: Cross-sectional scanning electron microgram of p++-Si/ $\alpha\text{-Li}_5\text{AlO}_4$ / IZO film

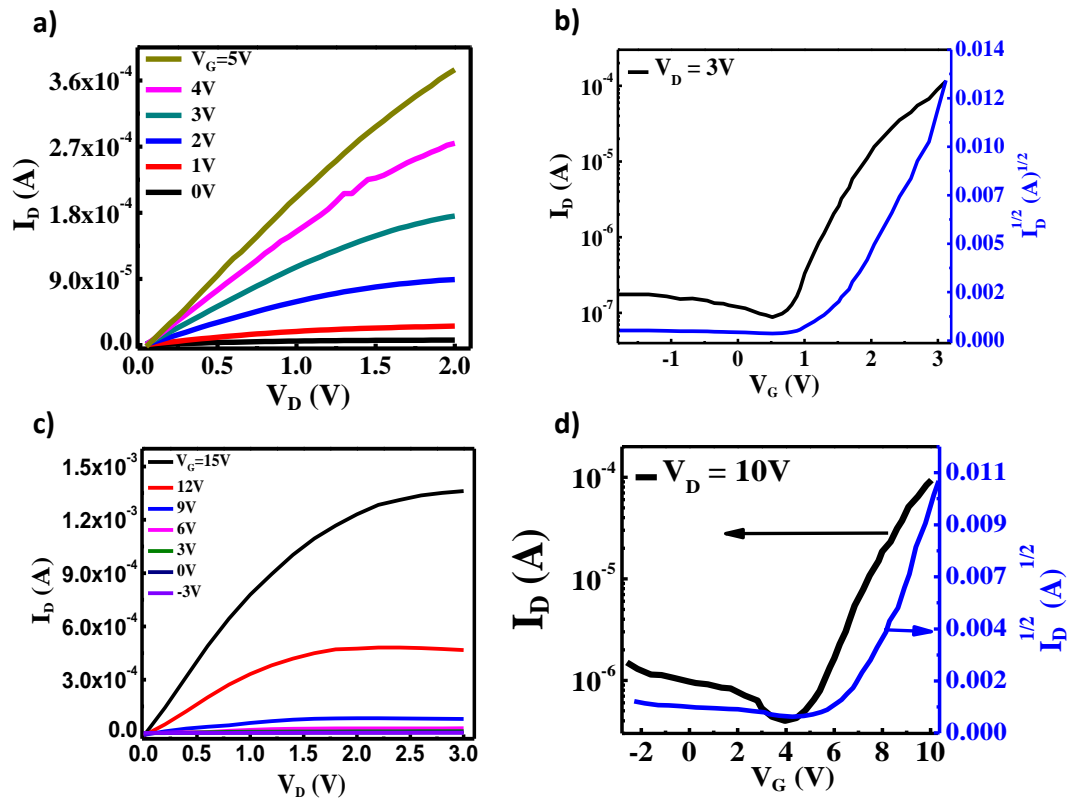


Fig. 4S The output characteristics for TFT fabricated with a) β - Li_5AlO_4 c) Li_5AlO_4 dielectric. Transfer characteristics for TFT fabricated with b) β - Li_5AlO_4 d) Li_5AlO_4 dielectric.

Table 1S: Comparison with recently published other high – k dielectric TFT

Dielectric Materials	Semiconductor	Fabrication Route	Capacitance (C) nFcm ⁻²	Mobility (μ) cm ² V ⁻¹ Sec ⁻¹	Product of capacitance and mobility (μ.C) nF V ⁻¹ Sec ⁻¹	Novelty	Reference
α-Li ₅ AlO ₄	IZO	Solution - Processed	332	21.4	7304	New TFT gate dielectric. High capacitance and mobility (μ.C) which result high current density TFT	This work
HfLaO _x	ZnO	Solution - Processed	190.09	1.6	330.15	Solution processed TFT gate dielectric	1
LiO _x	In ₂ O ₃	Solution - Processed	465	5.7	2650	New sol-gel derived TFT gate dielectric	2
Strontium titanate	Pentacene, CuPc	RF magnetron sputtering	41	2.0	2.46	Flexible device	3
Strontium oxide (SrO _x)	In ₂ O ₃	Solution - Processed	350	5.6	1963	Solution processed TFT gate dielectric	4
Magnesium titaniumoxide (Mg _{0.6} Ti _{0.4} O)	IZO	Solution - Processed	50	3.4	170	New sol-gel derived TFT gate dielectric	5

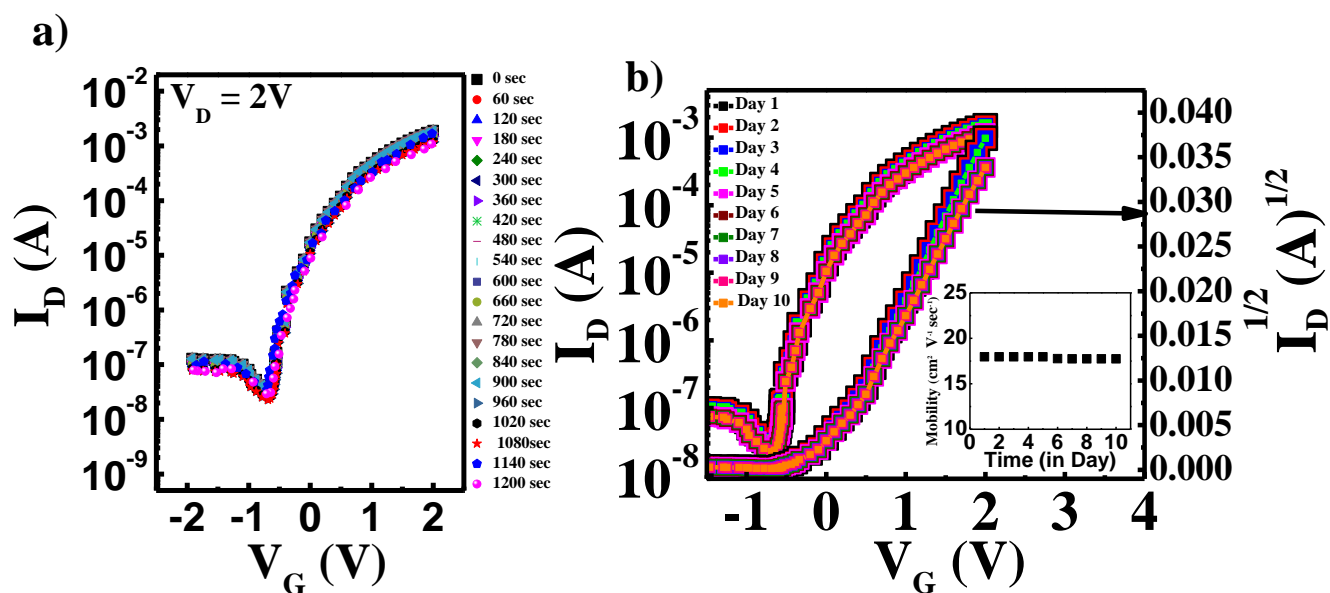


Fig. 5S Stability test of a α-Li₅AlO₄ dielectric TFT a) bias stress stability b) ambient atmosphere storage stability

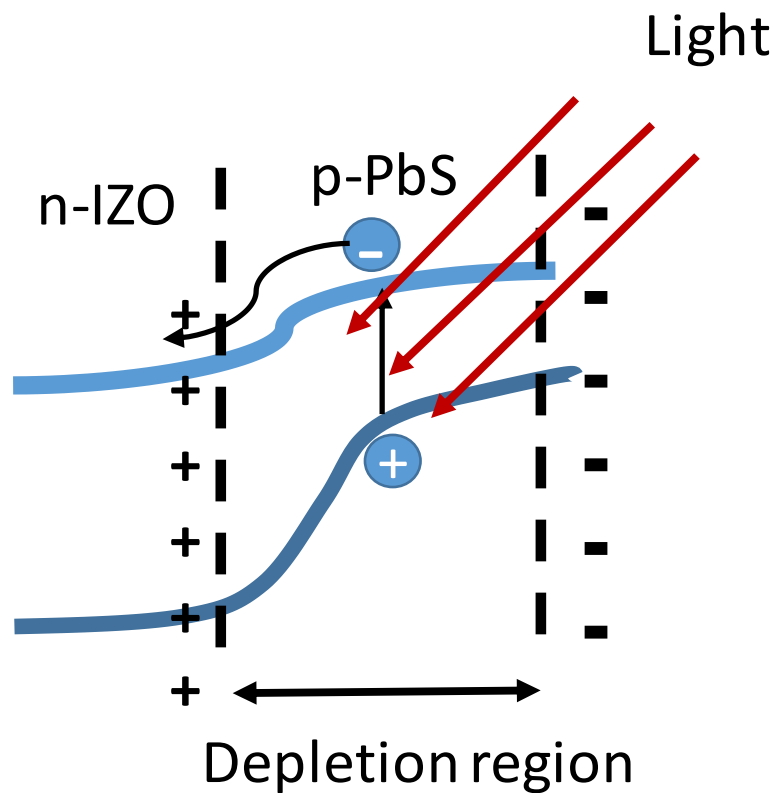


Fig. 6S Depletion layer formation of p-PbS/n-IZO heterojunction and photogenerated e-h separation due to the effect of barrier potential.

References:

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